

**THE FORUM ON THE SCIENCE AND TECHNOLOGY OF  
SILICON MATERIALS 2003**

**Shonan Village Center**

<http://www.jatis.jp/siliconforumhp/silicontop.html>

Organized by: Organizing Committee of the Silicon Materials Science and Technology Forum  
Supported by: The 145th Committee on Processing and Characterization of Crystals of JSPS  
The Japan Society of Applied Physics



**Organizing Committee:**

Chairman: K. Sumino (Professor Emeritus, Tohoku Univ.)

Members:

H. Yamada-Kaneta (Fujitsu Laboratories Ltd.): Program Chair	
H. Ono (Japan Fine Ceramics Center)	M. Suezawa (Tohoku Univ.)
S. Murakami (Hitachi, Ltd.)	M. Tajima (Inst. Space and Astro. Sci.)
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K. Nakai (Wacker NSCE Corp.)	H. Nakashima (Kyushu Univ.)
K. Nakamura (Komatsu Electric Metals Co. Ltd.)	K. Kashima (Toshiba Ceramics Co., Ltd.)

**Conference Site:** International Conference Hall,  
Shonan Village Center (<http://www.shonan-village.co.jp>)

**Dates:** Start (Registration) at 11 a.m., Nov. 25 (Tue); End at 4:00 p.m., Nov. 27 (Thu), 2003

**Forum aims to:**

1. Activate beyond-border confluence of the basic and application researches that are indispensable for establishing new technologies for device-oriented silicon and silicon-related materials.
2. Develop all-attendee-participating discussion that bears the breaking-through of the facing problems in the device fabrication technologies and industries.
3. Re-educate researchers and engineers who are concerned with the scientific and/or technological fields.

**Scope:** To develop and innovate the technologies and their research basis of the device-oriented silicon materials, we hold this Forum with the above-mentioned purposes. Though the Forum mainly comprises the invited talks, the poster presentations are also welcomed. We have ample time for poster presentations, and each poster is given the 4-minute introductory talk. The papers presented are all included in the Forum Proceedings. Those who wish to present the paper are requested to submit the manuscript in the following manner.

**Manuscripts:**

Two copies of the manuscript should be sent to T. Tamura, the Forum Secretary. The address is given below. The manuscript should be prepared in the camera-ready form with high-quality white sheets of the A4-size. There is no special (mandatory) format or limit of length for the manuscript. The manuscripts should arrive at T. Tamura by **October 10, 2003**.

<b>Fees:</b>	Type-A: <b>¥38,000</b>	Single room
	Type-B: <b>¥35,000</b>	Two-person-use of double room
	Type-C: <b>¥31,000</b>	Three-person-use of triple room

Fees of the type-A, -B, and -C all cover (1) Registration fee (11,000 yen), (2) Room charge per one person for the nights of 25th (Tue) and 26th (Wed) of Nov, 2003, (3) Six meals from the dinner of the 25th (Banquet) to the lunch of 27th, and (4) one copy of the Forum Proceedings. The rooms of the types A, B, and C all have bath with shower, toilet, and cable TV.

**Registration:** The registration form can be obtained on request. The request should be made by Web, E-mail, FAX to:

**Toshimitsu Tamura**  
**Secretary of Silicon Materials Forum**  
**Japan Technical Information Service**  
**Technical Development Bureau, Nippon Steel Corporation**  
**20-1 Shintomi Futtsu City, Chiba Prefecture 293-8511, Japan**

**Fax: +81 439 80 2738    E-mail: [t-tamura@re.nsc.co.jp](mailto:t-tamura@re.nsc.co.jp)    Web: <http://www.jatis.jp>**

**Deadline: October 31, 2003**

**Further Information:** Dr. H. Yamada-Kaneta (Fujitsu Laboratories Ltd.)

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